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- [c12] 12. The device of claim 11, wherein the blocking layer is a structure separate from the mask.
- [c13] 13. The device of claim 12, wherein the separate structure is an aperture.
- [c14] 14. The device of claim 12, wherein the separate structure is an additional mask.
- [c15] 15. The device of claim 13, wherein, the aperture is adjustable.
- [c16] 16. The device of claim 14 wherein the additional mask has an opaque region where the dummy fill shape is.
- [c17] 17. The device of claim 11 wherein the blocking layer is a low stress material deposited in a region on the mask covering the dummy fill shape.
- [c18] 18. The device of claim 11 wherein the blocking layer is deposited on a second membrane layer on the mask.
- [c19] 19. The device of claim 18 wherein the blocking layer is created by using a SOI starting substrate.
- [c20] 20. The method of claim 9 wherein the blocking layer is fabricated on a stencil mask.